

Measurement of silicon-sensor prototypes for the CMS High-Granularity Calorimeter Upgrade for HL-LHC

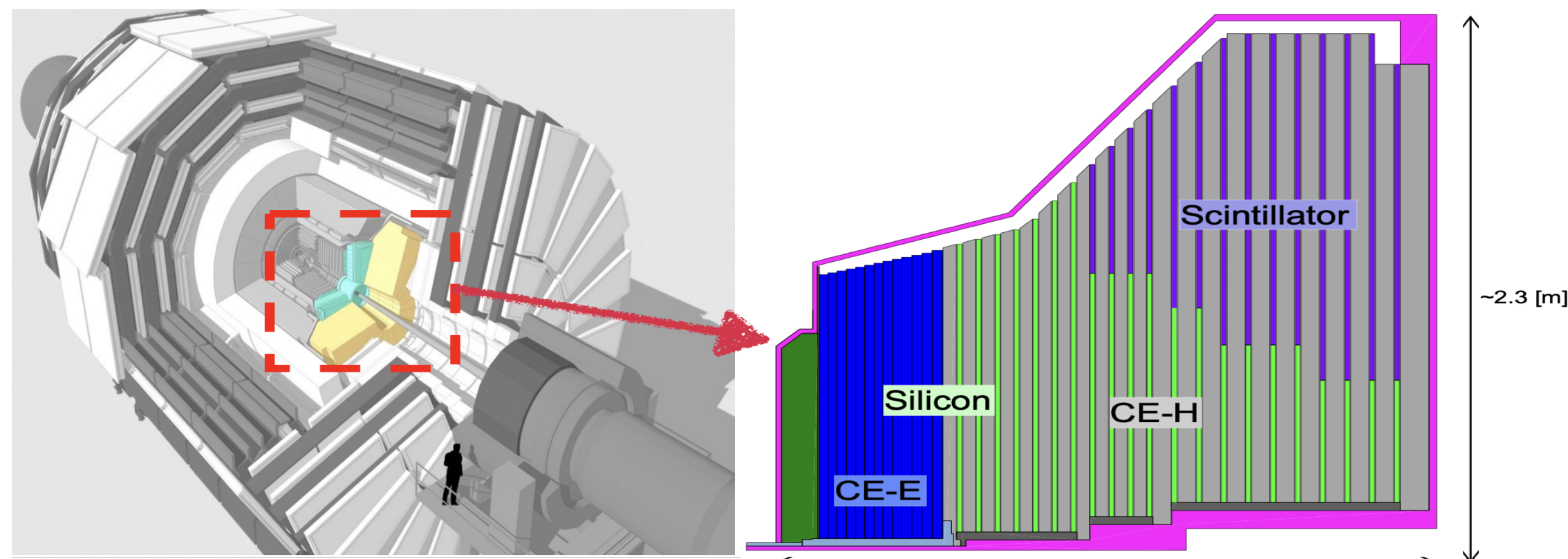
Chaochen Yuan, Eva Sicking, Philipp Zehetner, Huiling Hua, Kourosh Sarbandi, Marta Krawczyk, Pedro Almeida, Filip Moortgat, Thorben Quast on behalf of the CMS Collaboration



Overview of HGCal

Key parameters for the HGCal:

- ▶ HGCal covers $1.5 < \eta < 3.0$
- ▶ Full system maintained at -30°C
- ▶ ~ 26000 Si modules
- ▶ Power at end of HL-LHC: ~ 125 kW per endcap
- ▶ ~ 620 m² of silicon sensors
- ▶ ~ 370 m² of scintillators
- ▶ 6M Si channels, 0.6 or 1.2 cm² cell size

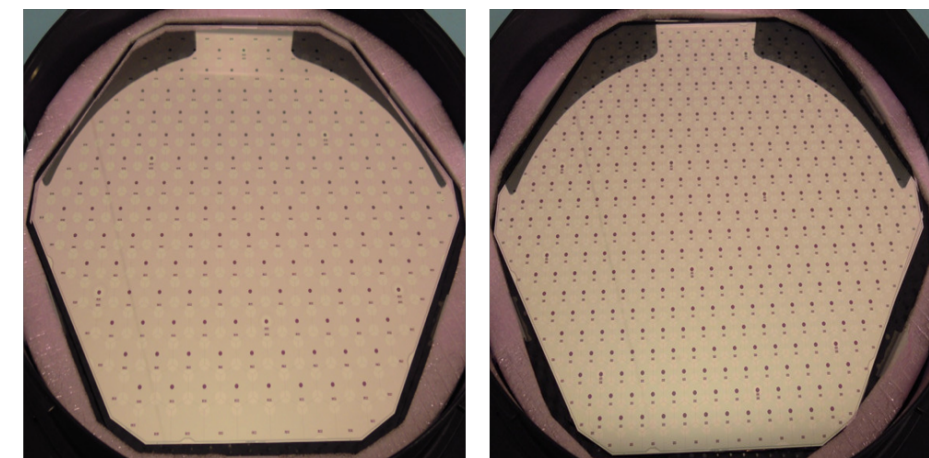
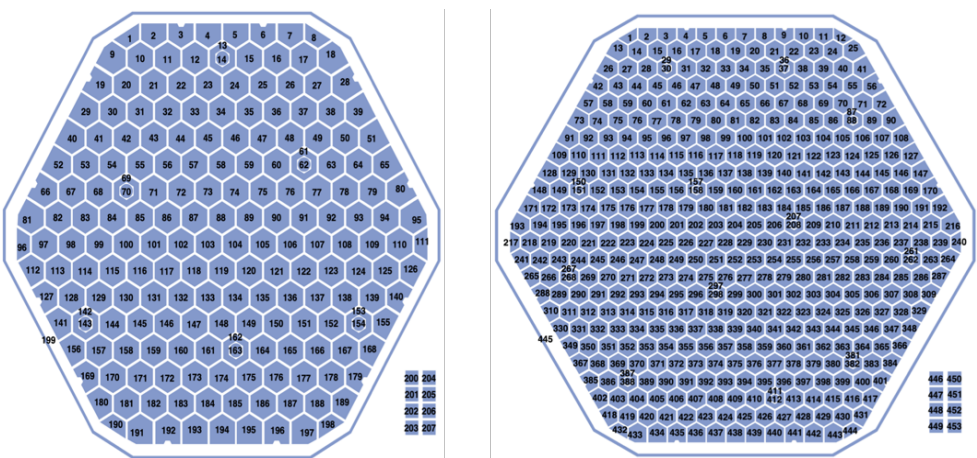


- ▶ **Endcap Electromagnetic calorimeter (CE-E):** Si, Cu & CuW & Pb absorbers, 26 layers, $27.7 X_0$.
- ▶ **Hadronic calorimeter (CE-H):** Si & scintillator, steel absorbers, 21 layers, $\sim 8.5 \lambda$
- ▶ **First 5D imaging calorimeter to operate in a collider experiment**

Silicon-sensor plays a crucial role

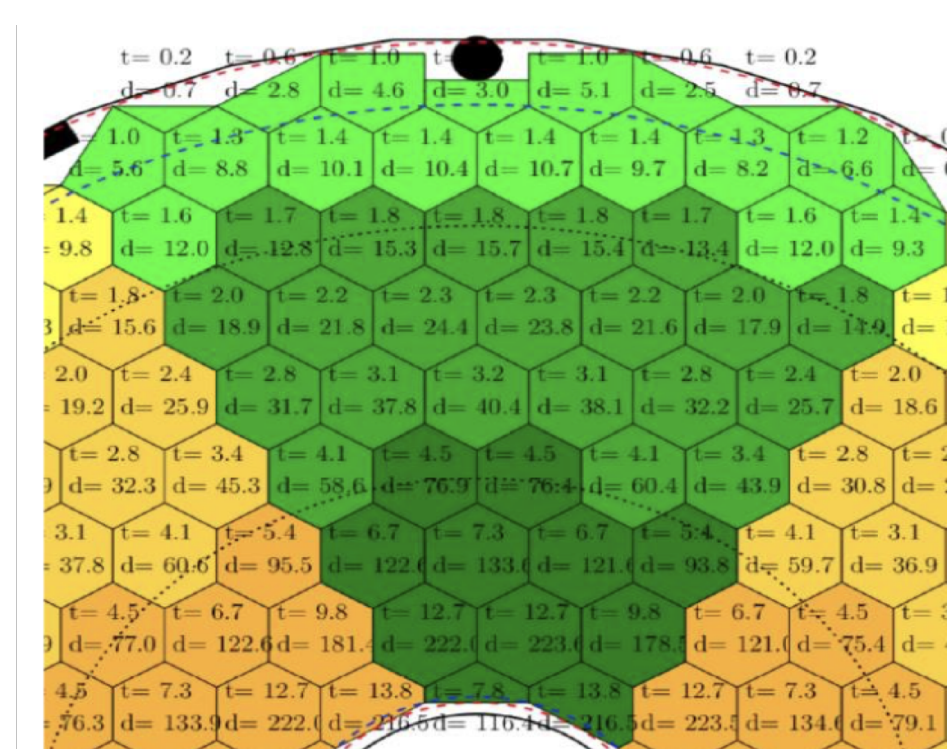
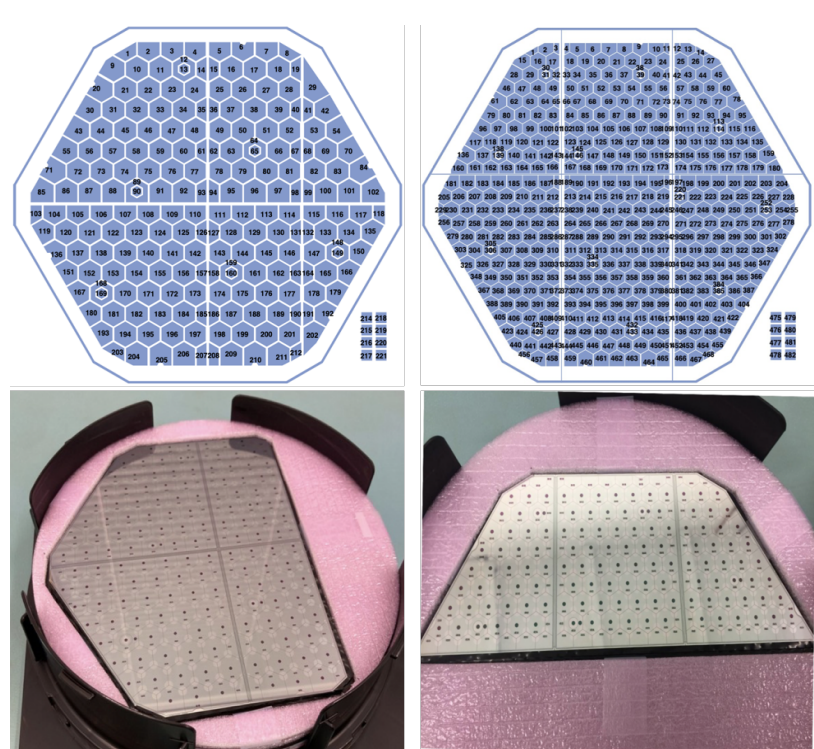
Overview of the sensor

Overview of full-sized sensors



- ▶ 8" full-sized sensors with different number of channels
- ▶ 3 different oxide quality: B, C, D
- ▶ 3 different thicknesses 120μm, 200μm, 300μm
- ▶ Some of them have been irradiated up to around 10^{16} neq/cm²

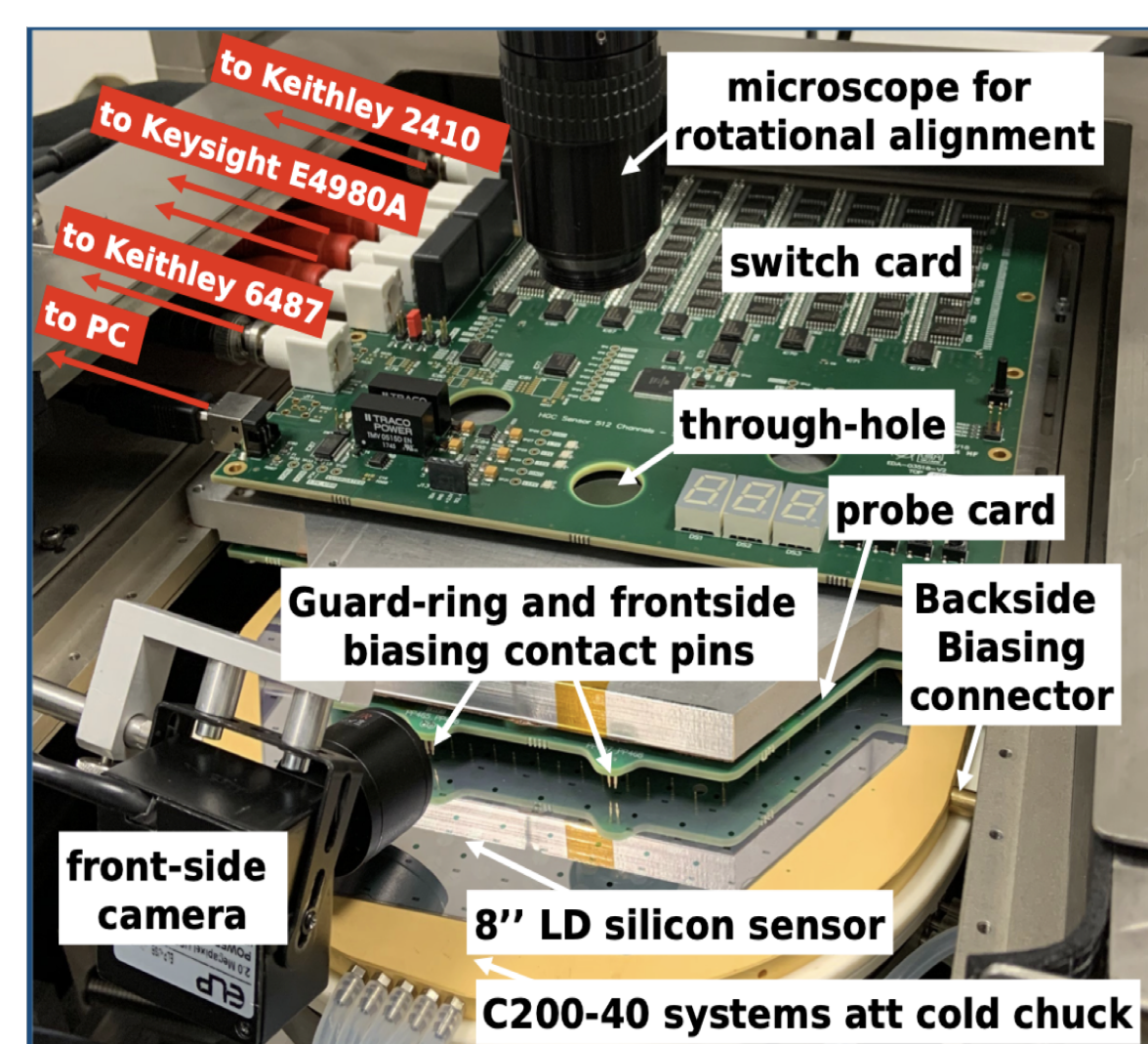
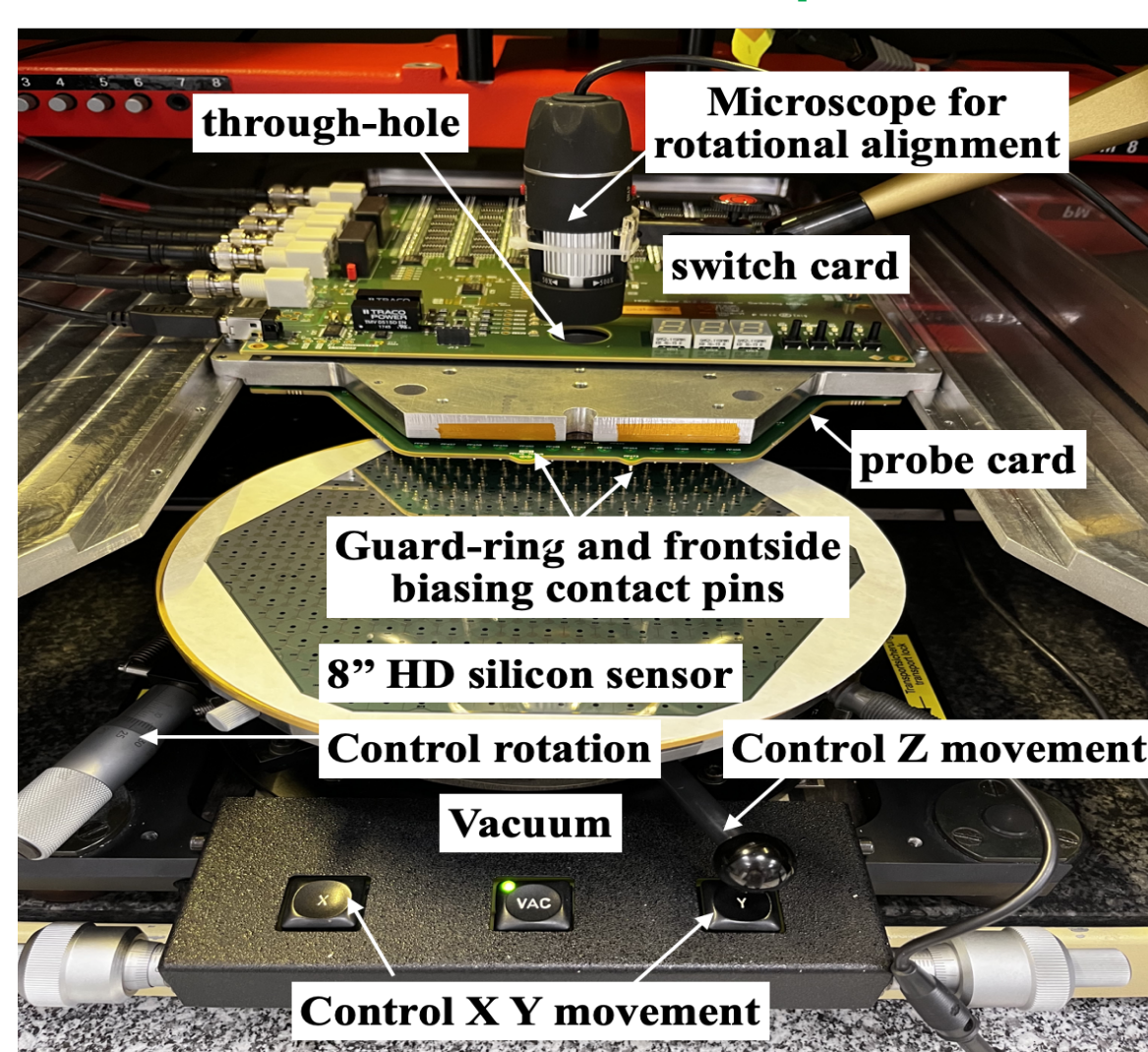
Overview of multi-geometry sensors



- ▶ 8" multi-geometry sensors with different number of channels
- ▶ 3 types of thicknesses
- ▶ Produce "partial sensors" to tile inner and outer edges
- ▶ 7 cut types, oxide quality: C

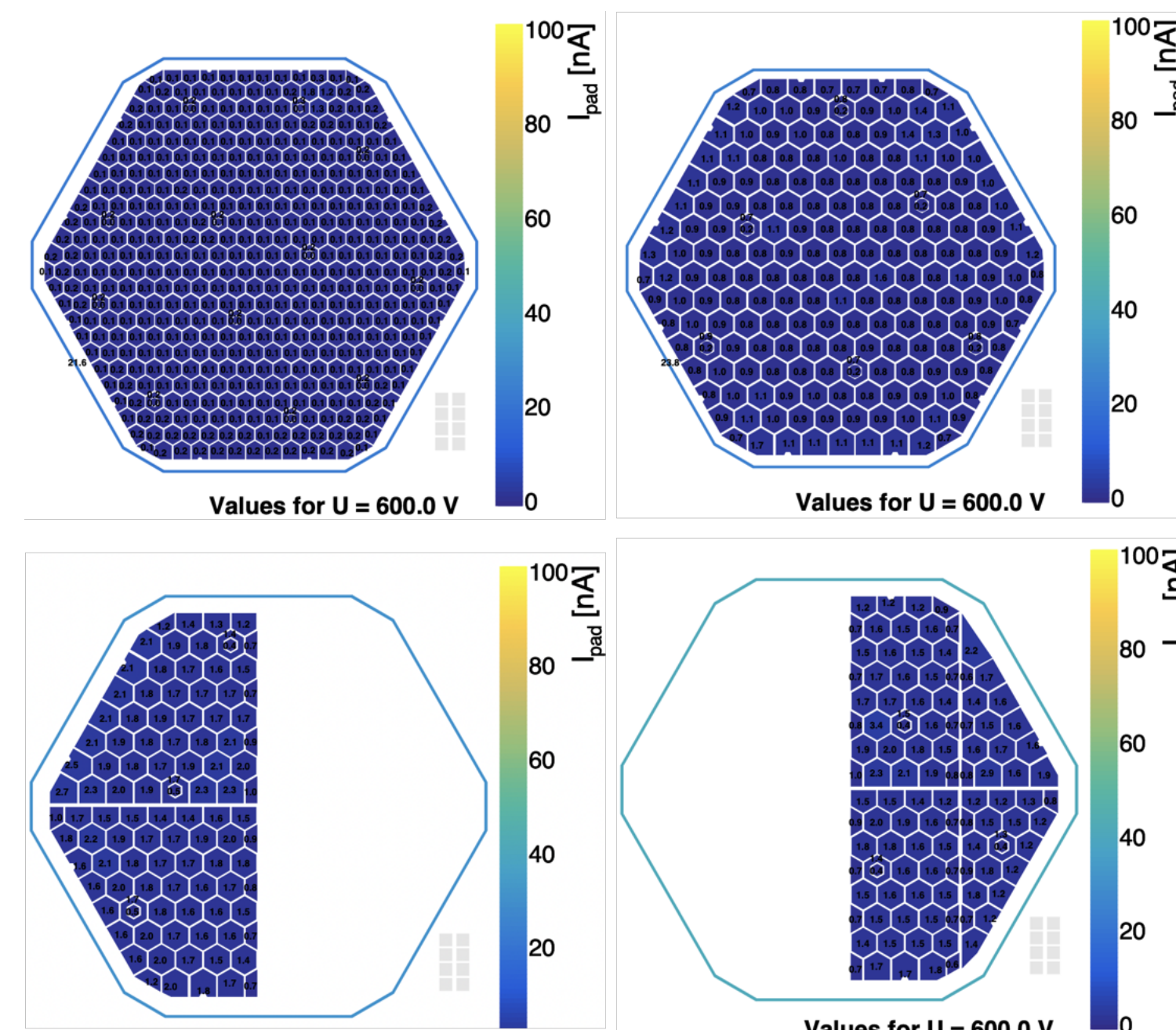
Measurement setup

Measurement setup



- ▶ Sensors on chuck with backside protection
- ▶ Temperature: room temperature; humidity: 4%-8%
- ▶ Voltage up to -850V
- ▶ Only used for non-irradiated sensors
- ▶ Sensors on chuck without backside protection
- ▶ Temperature: -40°C ; humidity: 4%-8%
- ▶ Voltage up to -850V from backside
- ▶ Annealing at 60°C , target time of 80 mins

Leakage current measurement before irradiation



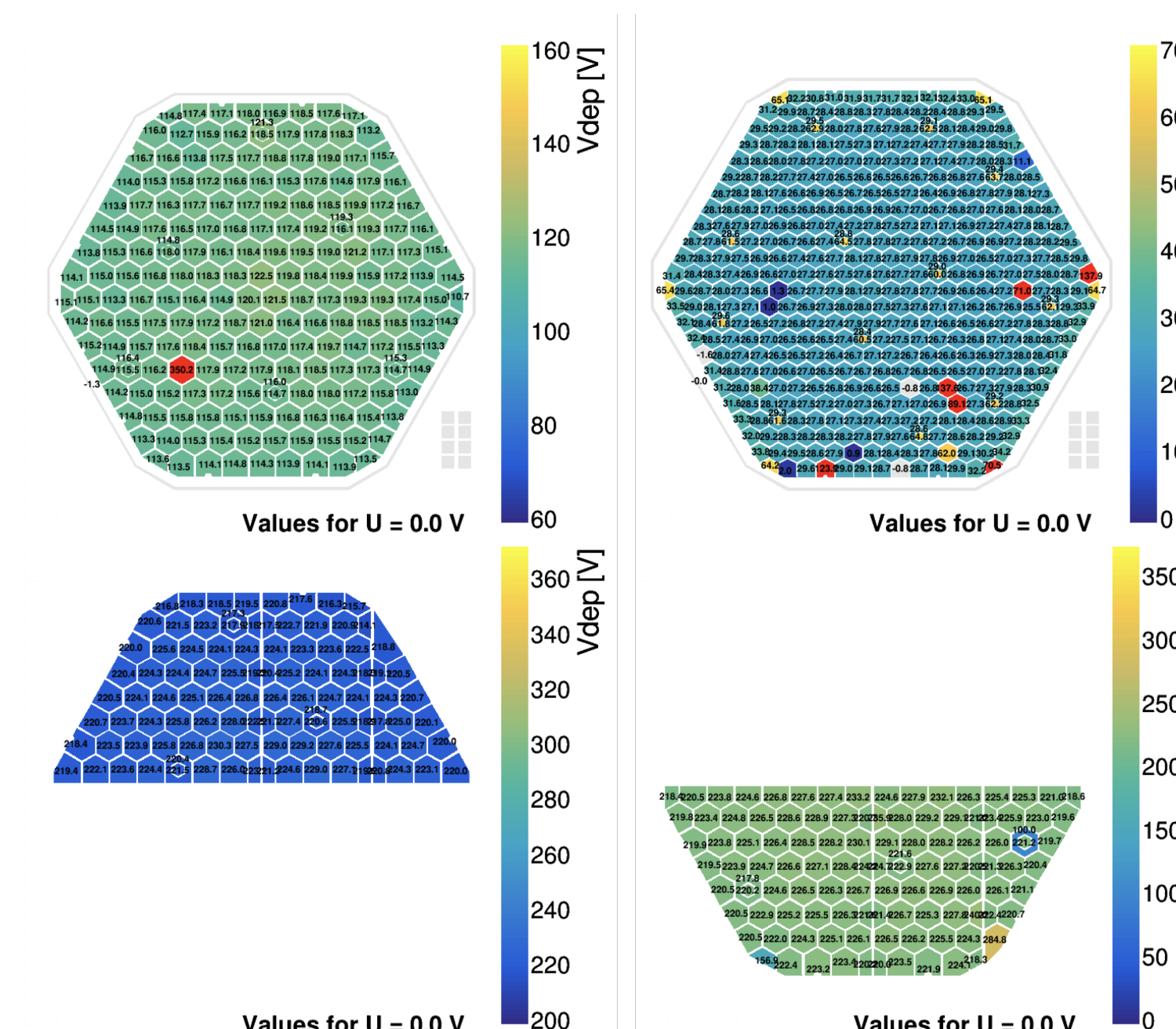
Grading

Global characteristics:

- ▶ Total current at 600V (I_{600}) $< 100 \mu\text{A}$
- ▶ $I_{800} < 2.5 * I_{600}$
- ▶ Bad pads number ≤ 8 (full-sized)
- ▶ Adjacent bad pads number ≤ 2
- Define **bad pads**:
- ▶ Pad current at 600V > 100 nA/pad

- ▶ Measure full-sized sensors, and multi-geometry-sensors.
- ▶ Leakage current less than $100 \mu\text{A}$ at 600V, all passed

Depletion voltage measurement before irradiation

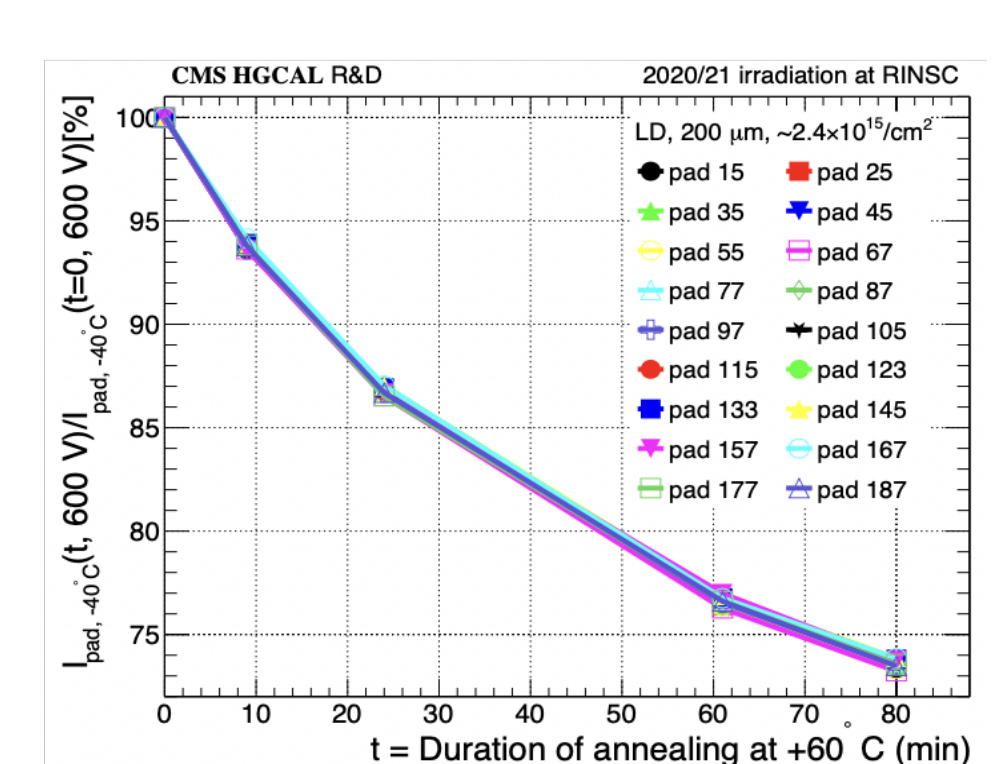
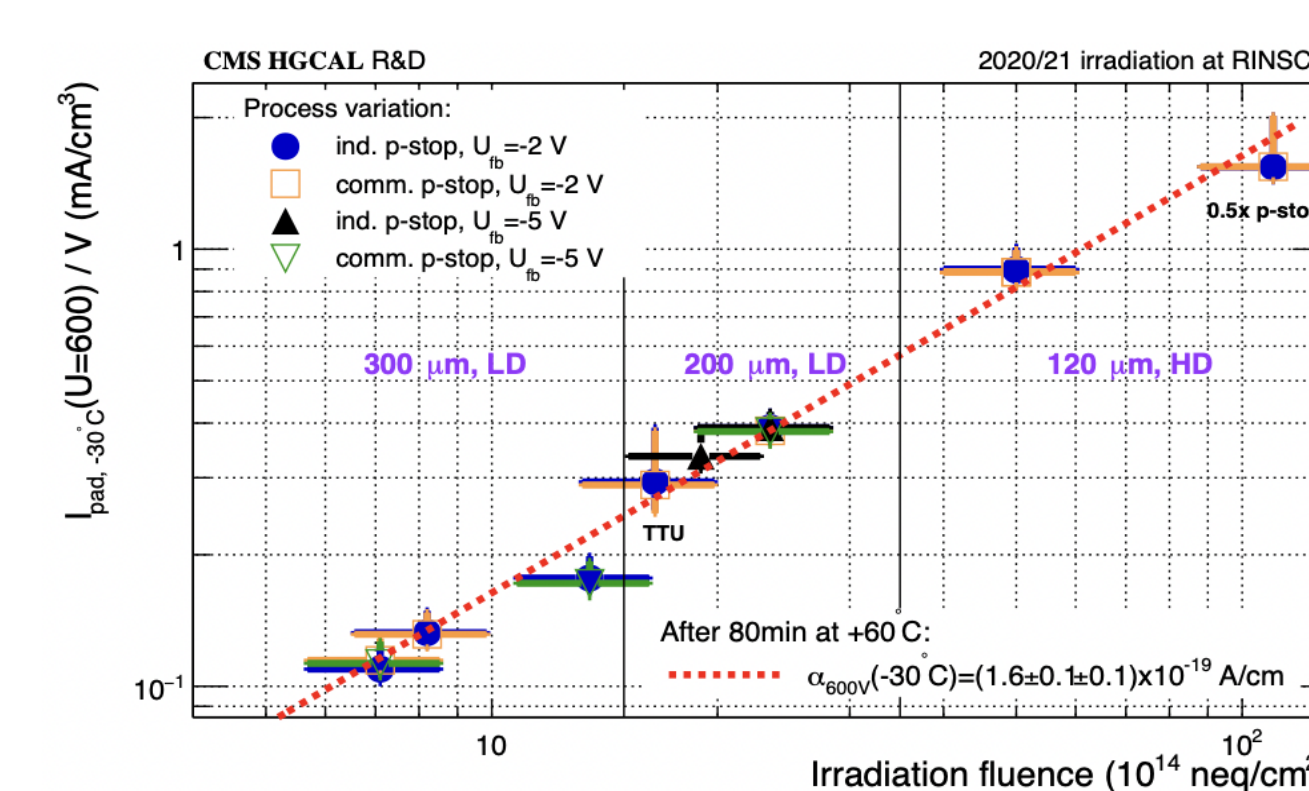


Grading

Global characteristics:

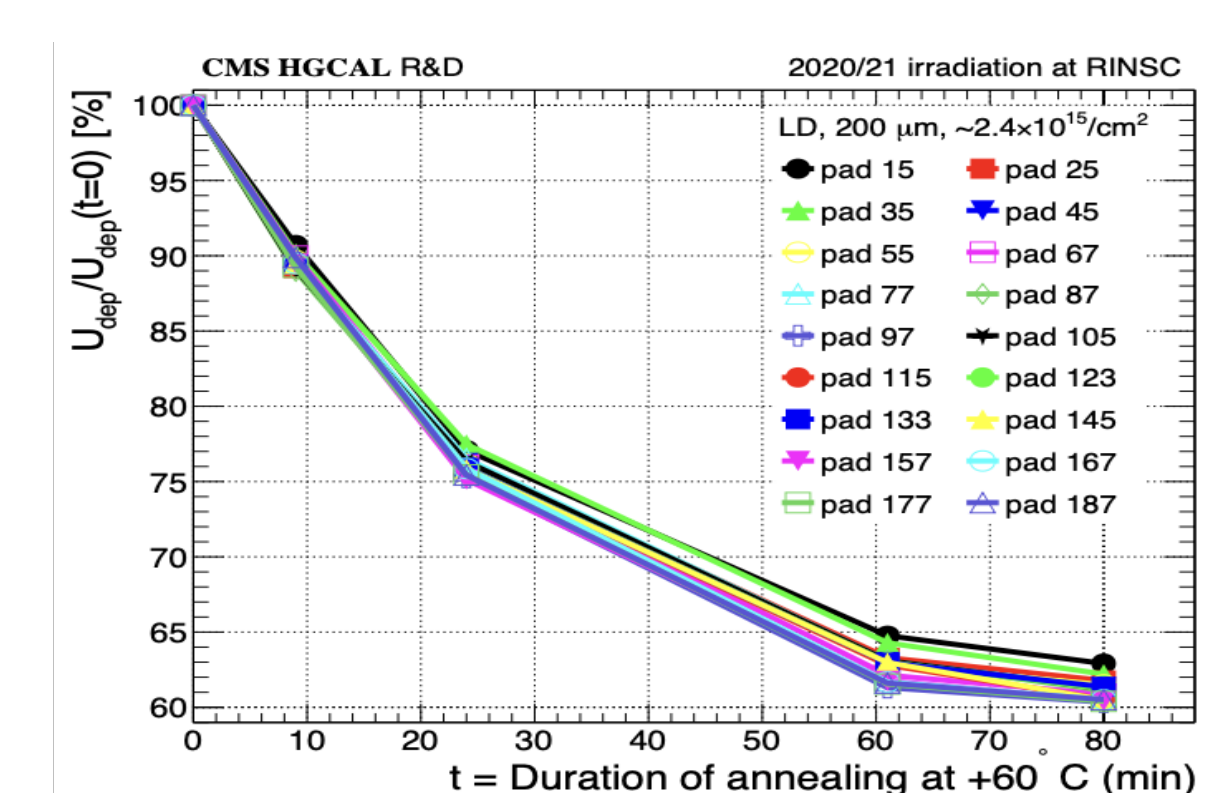
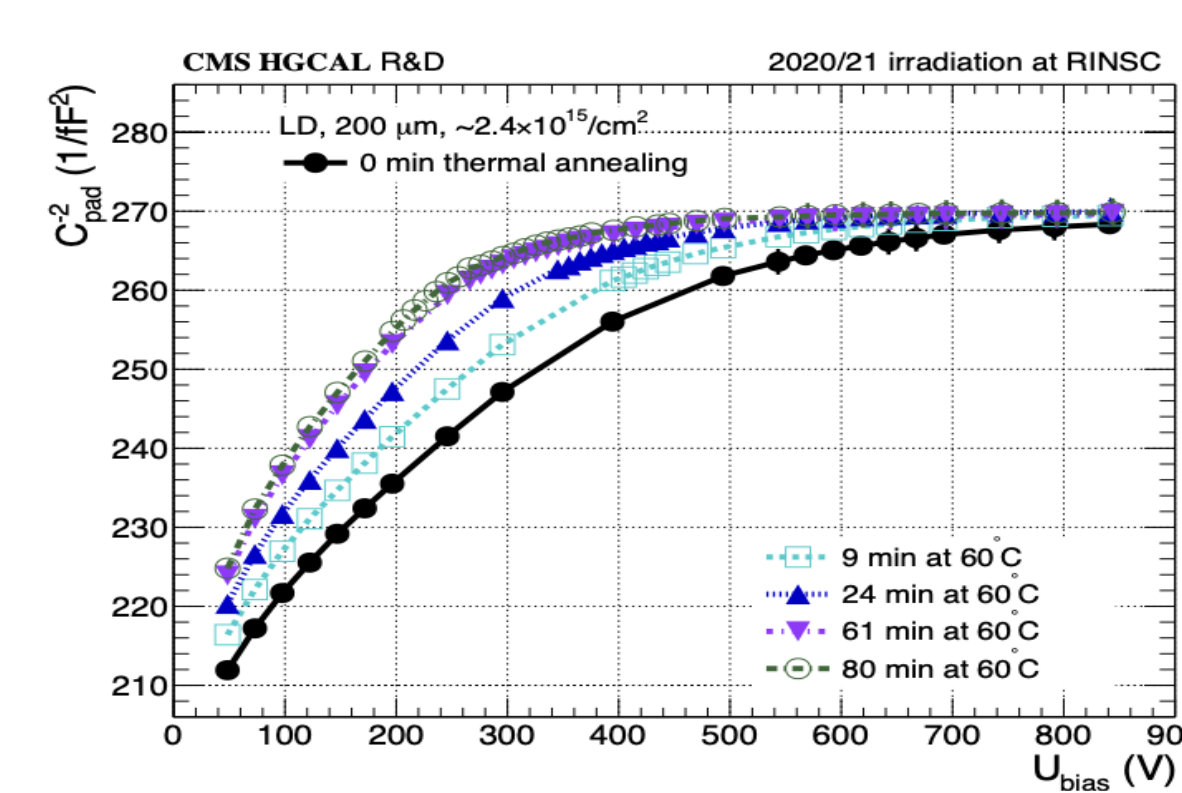
- ▶ Full depletion voltages V_{dep} : median of depletion voltages across cells
- ▶ $V_{dep} < 370\text{V}$ for 300μm thickness
- ▶ $V_{dep} < 160\text{V}$ for 200μm thickness
- ▶ $V_{dep} < 70\text{V}$ for 120μm thickness
- Depletion voltage sensitive to thickness
- Depletion voltage all passed the grading

Leakage current measurement after irradiation



- ▶ $\frac{\Delta I}{I} = \alpha * \Phi_{eq}$ (ΔI : change of leakage current, α : current related damage rate, Φ_{eq} : irradiation fluence, V : volume)
- ▶ Linear relationship between leakage current and irradiation fluence
- ▶ $\frac{\Delta I(t)}{\Delta I(0)} = be^{-\frac{t}{\tau}}$ (b : corresponding amplitude, t : annealing time, τ : time constant)
- ▶ Leakage current drop with annealing

Depletion voltage measurement after irradiation



- ▶ The change of depletion voltage is dominated by short annealing term $N_A = \Phi_{eq} * g * e^{-\frac{t}{\tau}}$ (g : introduction rate)
- ▶ Depletion voltage decreases with annealing time

Next step

- ▶ Start the irradiation test for multi-geometry sensors with higher fluence
- ▶ Measure pre-series sensors
- ▶ Prepare measurement infrastructure and procedure for mass measurement